Notice of Allowability	Application No.	Applicant(s)	
	09/620,708	KODAMA ET AL.	
	Examiner	Art Unit	
	John S. Chu	1752	<u> </u>
The MAILING DATE of this communication apperall claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RI of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in or other appropriate commercer GHTS. This application is	in this application. If not include unication will be mailed in due of	d course. <b>THIS</b>
1. $\boxtimes$ This communication is responsive to $\underline{11/21/03}$ .			
2. The allowed claim(s) is/are <u>1-25</u> .			
3. The drawings filed on are accepted by the Examiner	r.		
<ul> <li>4.  Acknowledgment is made of a claim for foreign priority unall a)  All b)  Some* c)  None of the:</li> <li>1.  Certified copies of the priority documents have</li> <li>2.  Certified copies of the priority documents have</li> <li>3.  Copies of the certified copies of the priority documents</li> </ul>	been received. been received in Applicati	on No	ion from the
International Bureau (PCT Rule 17.2(a)).			
* Certified copies not received:			
Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONM THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.	ENT of this application.		
5. A SUBSTITUTE OATH OR DECLARATION must be subm INFORMAL PATENT APPLICATION (PTO-152) which give	es reason(s) why the oath o		OTICE OF
6. CORRECTED DRAWINGS (as "replacement sheets") mus		,	
(a) ☐ including changes required by the Notice of Draftspers	=	w (PTO-948) attached	
<ol> <li>1) ☐ hereto or 2) ☐ to Paper No./Mail Date</li> <li>(b) ☐ including changes required by the attached Examiner's</li> </ol>		us in the Office action of	
Paper No./Mail Date	s Amendment / Comment t	ir in the Office action of	
Identifying indicia such as the application number (see 37 CFR 1 each sheet. Replacement sheet(s) should be labeled as such in the			back) of
7. DEPOSIT OF and/or INFORMATION about the deposit attached Examiner's comment regarding REQUIREMENT	sit of BIOLOGICAL MAT FOR THE DEPOSIT OF BI	ÉRIAL must be submitted. N OLOGICAL MATERIAL.	lote the
Attachment(s)			,
1. ☑ Notice of References Cited (PTO-892)	5. Notice of I	nformal Patent Application (PTC	)-152)
2. Notice of Draftperson's Patent Drawing Review (PTO-948)		Summary (PTO-413),	
Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date		./Mail Date s Amendment/Comment	
4. Examiner's Comment Regarding Requirement for Deposit		s Statement of Reasons for Allo	wance
of Biological Material	9. 🗌 Other	<b>_</b> :	
		John S. Chu Primary Examiner Art Unit: 1752	

## **REASONS FOR ALLOWANCE**

The following is an examiner's statement of reasons for allowance: The claimed invention is drawn to the following:

- 1 (Amended). A positive photoresist composition comprising:
- (A) a compound capable of generating an acid upon irradiation with actinic rays or radiation and

(B) a resin capable of decomposing under the action of an acid to increase the blubility in alkali, containing a repeating unit represented by the following formula (AI):

wherein R represents hydrogen atom, a halogen atom, a substituted or unsubstituted alkyl group having from 1 to 4 carbon atoms, A' represents a single bond and B represents a group represented by formula (I):

$$\begin{pmatrix} R_3 \\ R_2 \end{pmatrix}_m \begin{pmatrix} R_1 \\ R_5 \end{pmatrix}_n$$

$$\begin{pmatrix} R_3 \\ R_5 \end{pmatrix}_{R_6}$$

$$\begin{pmatrix} R_3 \\ R_5 \end{pmatrix}_{R_7}$$

$$\begin{pmatrix} R_1 \\ R_5 \end{pmatrix}_{R_7}$$

$$\begin{pmatrix} R_1 \\ R_5 \end{pmatrix}_{R_7}$$

wherein  $R_1$  represents hydrogen atom or an alkyl group having from 1 to 4 carbon atoms, which may have a substituent,  $R_2$  to  $R_7$ , which may be the same or different, each represents hydrogen atom, an alkyl group which may have a substituent, a cycloalkyl group which may have a substituent or an alkenyl group which may have a substituent, provided that at least one of  $R_6$  and  $R_7$  is not a hydrogen atom and  $R_6$ 

and R<sub>7</sub> may combine to form a ring, and m and n each independently represents 0 or 1, provided that m and n are not 0 at the same time.

- 9 (Amended). A positive photoresist composition for far ultraviolet exposure, comprising:
- (A) a compound capable of generating an acid upon irradiation with actinic rays or radiation,
- (B) a resin capable of decomposing under the action of an acid to increase the solubility in alkali, containing a repeating unit having a group represented by the following formula (I), and
  - (C) a fluorine-containing and/or silicon-containing surfactant:

$$\begin{pmatrix} R_3 \\ R_2 \end{pmatrix}_m \begin{pmatrix} R_1 \\ R_5 \\ R_6 \end{pmatrix}_n$$
 (1)

wherein R<sub>1</sub> represents hydrogen atom or an alkyl group having from 1 to 4 carbon atoms, which may have a substituent, R<sub>2</sub> to R<sub>7</sub>, which may be the same or different, each represents hydrogen atom, an alkyl group which may have a substituent, a cycloalkyl group which may have a substituent or an alkenyl group which may have a substituent, provided that at least one of R<sub>6</sub> to R<sub>7</sub> is not a hydrogen atom and R<sub>6</sub>

and  $R_7$  may combine to form a ring, and m and n each independently represents 0 or 1, provided that m and n are not 0 at the same time.

- 18 (Amended). A positive photoresist composition for far ultraviolet exposure, comprising:
- (A) a compound capable of generating an acid upon irradiation with actinic rays or radiation,
- (B) a resin capable of decomposing under the action of an acid to increase the solubility in alkali, containing a repeating unit represented by the following formula (AI), and
- (D) a solvent containing the following solvent (a) in an amount of 60% to 90 wt % based on the entire solvent:
- (a) at least one first solvent selected from propylene glycol monomethyl ether acetate, propylene glycol monomethyl ether propionate, methyl 3-methoxypropionate, ethyl 3-methoxypropionate, methyl 3-ethoxypropionate and ethyl 3-ethyoxypropionate;

wherein R represents hydrogen atom, a halogen atom, a substituted or unsubstituted alkyl group having from 1 to 4 carbon atoms, A' represents a single bond and B represents a group represented by formula (I):

$$\begin{pmatrix} R_3 \\ R_2 \end{pmatrix}_m \begin{pmatrix} R_1 \\ R_5 \end{pmatrix}_n$$

$$\begin{pmatrix} R_3 \\ R_6 \end{pmatrix}$$

$$\begin{pmatrix} R_1 \\ R_6 \end{pmatrix}$$

wherein  $R_1$  represents hydrogen atom or an alkyl group having from 1 to 4 carbon atoms, which may have a substituent,  $R_2$  to  $R_7$ , which may be the same or different, each represents hydrogen atom, an alkyl group which may be substituent, a cycloalkyl group which may have a substituent or an alkenyl group which may have a substituent, provided that at least one of  $R_6$  and  $R_7$  is not a hydrogen atom and  $R_6$  and  $R_7$  may combine to form a ring, and m and n each independently represents 0 or 1, provided that m and n are not 0 at the same time.

The response of November 21, 2003 contains a Terminal Disclaimer, which overcomes the last outstanding issue for an obviousness-type double patenting rejection over 2002/0006576 A1 to SATO et al.

None of the prior art references of record disclose the claimed invention as recited in claims 1, 9 and 18. The inventive step in claim 1 is to the resin having the formula (AI). Claim 9 recites a resin having a group of formula (I) however also recites the presence of a fluorine-containing and/or silicon-containing surfactant, which is not disclosed in any of the references of record. Claim 18 recites the resin of claim 1 and further recites a least one first solvent as seen

above. Likewise, none of the references of record disclose the claimed invention in claim 18 as recited in the claims above.

Newly cited reference to SATO et al '655 discloses a group Y in claim 1 which meets formula (I) in claim 9, however SATO et al lacks the use of the claimed fluorine-containing and/or silicon-containing surfactants as recited. Further the references fails to disclose the claimed group of formula (AI) in claims 1 and 18.

Because none of the references of record disclose the claimed invention as recited claims 1-25 are seen as allowable and passed to issue.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Examiner Chu whose telephone number is (571) 272-1329. The examiner can normally be reached on Monday - Friday from 9:30 am to 6:00 pm.

The fax phone number for the USPTO is (703) 872-9306.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the Group receptionist whose telephone number is (703) 308-0661.

John S. Chu

Primary Examiner, Group 1700

J.Chu March 3, 2004